

FORM PTO-1449		Docket Number (Optional) 341.6910USQ	Application Number
INFORMATION DISCLOSURE CITATION IN AN APPLICATION		Applicant Pasqualoni et al.	
(Use several sheets if necessary)		Filing Date Not Yet Assigned	Group Art Unit Not Yet Assigned

U. S. PATENT DOCUMENTS

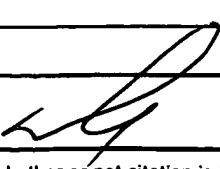
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
mm	3,170,273	2/23/65	Walsh et al.			
mm	3,527,028	9/26/67	Donald R. Oswald			
mm	4,050,954	9/27/77	Jagtar S. Basi			
mm	4,169,337	10/2/79	Charles C. Payne			
mm	4,304,575	12/8/81	Charles C. Payne			
mm	4,462,188	7/31/84	Charles C. Payne			
mm	5,139,571	8/18/92	Deal et al.			
mm	5,230,833	7/27/93	Romberger et al.			
mm	5,246,624	9/21/93	Miller et al.			
mm	5,314,843	5/24/94	Yu et al.			
mm	5,340,370	8/23/94	Cadien et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

mm	Carpio et al., "Initial Study on Copper MCP Slurry Chemistries", Thin Solid Films, 1995. <i>no month</i>
mm	Stavreva et al., "Chemical-Mechanical Polishing of Copper for Interconnect Formation", Microelectronic Engineering, 1997. <i>no month</i>
mm	In Proceedings of the CMP-MIC conference "Development of a 1:1:1 Slurry for Tantalum Layer Polishing", February 1999.

EXAMINER	DATE CONSIDERED
	1/27/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP §609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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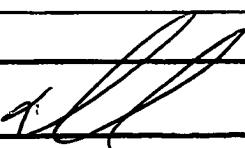
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
mm	5,607,718	3/4/97	Sasaki et al.			
mm	5,656,097	8/12/97	Olesen et al.			
mm	5,695,384	12/9/97	Howard R. Beraton			
mm	5,750,440	5/12/98	Vanell et al.			
mm	5,770,095	6/23/98	Sasaki et al.			
mm	5,908,509	6/1/99	Olesen et al.			
mm	5,954,997	9/21/99	Kaufman et al.			
mm	5,980,775	11/9/99	Grumbine et al.			
mm	5,993,685	11/30/99	Currie et al.			
mm	5,996,595	12/7/99	Olesen et al.			
mm	6,010,962	1/4/00	Liu et al.			

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OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

mm	Kumar et al., "Chemical-Mechanical Polishing of Copper in Glycerol Based Slurries", Materials Research Society Symposium Proceedings, 1996. (no month)
mm	Gutman et al., "Chemical-Mechanical Polishing with Oxide and Polymer Interlevel Dielectrics", Thin Solid Films, 1995. (no month)
mm	Lou et al., "Stabilization of Alumina Slurry for Chemical-Mechanical Polishing of Copper", Langmuri, 1996. (no month)

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MM	6,171,352	01-2001	Lee et al.	51	307	
MM	6,461,227	10-2002	Fang Mingming	451	41	
MM	6,325,705	12-2001	Burke et al.	451	288	
MM	6,063,306	05-2000	Kaufman et al.	252	79.4	
MM	6,136,711	10-2000	Grumbine et al.	438	692	
MM	2002/0032987	03-2002	Steckenrider et al.	51	309	
MM	2002/0003225	01-2002	Hampden-Smith et al.	252	79.1	
MM	6,171,352	01-2001	Lee et al.	51	307	
MM	6,461,227	10-2002	Fang, Mingming	45	141	
MM	6,325,705	12-2001	Burke et al.	451	288	
MM	6,036,306	05-2000	Kaufman et al.	252	79.4	

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						YES	NO
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Sheet 1 of 1

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Docket Number (Optional)

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341 69

Applicant

Fasquare

Group Art Unit

December 1, 2003

Not Yet Assigned

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